National Synchrotron Light Source II



Powder Diffraction Beamline

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Scientific Mission of NSLS-II PD Beamline"

(user and workshop input http://www.bnl.gov/nsls2/workshops/UserWorkshop.asp)

The proposed powder diffractometer at NSLS-II will be the US' only high-resolution instrument capable of collecting data at high energies (20 keV to 100 keV). This will make it ideal for *in situ* and time resolved studies of samples held in environmental cells.

High energy for atomic pair distribution function method (PDF) and Environmental Cell (e.g. DAC) work.

Some scientific thrusts/importance for high energy X-ray elastic scattering

Water and ice *Structures and transformations* (0.1 – 50 GPa) Novel clathrates *Energy resources, hydrogen/energetic gas storage* Dense liquids, melts, glasses *Why is gallium a liquid at HP? Glass technology* Pressure induced amorphization *New materials with new properties under pressure* Strongly correlated systems *Structures, dynamics, and mechanisms. Novel behavior* Structures of new ferroelectrics *New materials and pressure tuning behavior* Nanomaterials *Differences between bulk and nano-materials*





Beamline Requirements and Specifications

- Several itterations of beamline requirements over the past 6 months settled on high-energy high-resolution PD capabilities - in collaboration with discussion with potential BAT members.
- In early stages of BAT formation:- workshop on November 30th, 2007.

<u>Major Specifications:</u>

- Attenuators to remove significant power load from the low energy region.
- Mirror: 1.5 m long Pt-coated. 20 40 keV range. 2 mrad incidence angle.
- Monochromator. Sagitally Focusing Asymmetric Laue. (In use at NSLS X17 and tested at X7b)
- Energy Range. 20 keV to 100 keV (High energy end determined by Damping Wiggler Output)
- Energy Resolution. dE/E 1x10⁻⁴ to dE/E 1x10⁻³
- Vertical Divergence. Mirror acting as collimator ~ <5 Orad rms or ~ 100 Orad (mirror out natural x-ray beam divergence)
- Vertical Focusing: 1.5 m long mirror acting as ~ 1:1 focusing device. 400 Om (fwhm) (assuming 3 Orad rms figure error).
- Horizontal Focusing: Sagitally Focusing Laue (1:1) ~ 300 Om (fwhm). 0.5 m long Horizontally Focusing Graded-Multilayer (~28:1) ~ 14 Om (fwhm) (slope error included)
- Flux on Sample see later!





Beamline Requirements and Specifications

• Photon Beam Stability Requirements

(NSLS-II stability workshop page: www.bnl.gov/nsls2/workshops/Stability_Wshop_4-18-07.asp)

• Operational Modes: crystal analyzer (angular stability), area detector (position stability).

<u>10 μ m spatial stability</u> in both x-and-y (area detector)

<u>1 μ rad angular stability</u> in vertical diffraction plane (analyzer mode).

Monochromator temperature stability < 10°C





Beamline Layout - Overview



Experimental Hutch 1: High-Energy, High-Resolution: Costed

Experimental Hutch 2: 'Routine' Powder Diffraction with Area Detector. Enclosure costed. Equipment to be used from NSLS-I stock. Possibly served by canted wiggler device or as an additional endstation.





Damping Wiggler Insertion Device

- Damping Wiggler (high- β straight).
- Damping Wiggler will provide high flux, high brightness hard x-rays (E_{critical}~10.8 keV).
- Current thinking: either one 7m long device or two 3.5 m devices one canted.

machine and damping wiggler parameters

Eo	3 GeV
lo	500 mA
N periods	70
λ_{u}	10 cm
В	1.8 Tesla
k	16.81

rms electron beam values

σ_{χ}	99 µm
σ_z	5.5 µm
σ_{χ}'	5.5 µrad
σ_{z}'	1.8 µrad

Total Power (integrated over all angles) ~ 65 kW Power Density ~ 54.9 kW/ mrad²





Damping Wiggler: Flux and Brightness



Flux Comparison between NSLS-II DW and X17 SCW





Brightness Comparison between NSLS-II DW and X17 SCW



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Managing the Power Load & Energy Range





Power Load Considerations



Control acceptance by fixed aperture in front end and/or by adjustable 4 slit mechanism.

Total Power

64.5 kW

1 mrad [hor] x 0.1 mrad [ver]: 5.2 kW

corresponds to a 1.5m long mirror operating at a grazing incidence angle of 2 mrad in the front optical enclosure (~ 30 m from source point).



Aperturing in Front End





Power Load Considerations - Filtering



Reduce power load on critical optical components by filtering out the low energy x-rays.

(Energy range of beamline > 20 keV)

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2 mm of C removes ~ 2 kW of power 5 mm of C removes ~ 3 kW of power

....and beamline can operate effectively above 20 $\ensuremath{\text{keV}}$

Acceptance: 1 mrad x 0.1 mrad @ 30 m





Vertically Focusing/Collimating Mirror

Length: 1.5 m, mirror bender Pt Coated, 2 mrad grazing incidence Vertically Focusing (~ 1:1) or collimating Operating Energy Range (with Laue) 20 - 40 keV

Material: Pt 2.00000 mrad; rough rms=3.00000 Ang.

Mirror FEA

'Worst Case' Scenario:
Total Power: 7 kW
Power Density: 0.18 W/mm²
Black: Si mirror with side cooling
Red: Glidcop mirror directly cooled

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Double-Crystal Laue Monochromator

Sagittally Focusing Double-Crystal Laue Mono

In use at X17, (tested for X7B)

Dr. Zhong Zhong design

Can take a large horizontal fan (> 3 cm) and focus it down to a few hundred microns

Asymmetric Bent Si (111), Si (311)

Band-Width (in focusing mode) dE/E ~ few x 10^{-3} for Si(111) ~5x10⁻⁴ for Si(311) - great for area detector work. Need to unbend for high-resultion worki.e. no focusing - acts like in normal Bragg case.

Energy Range: 20 to 100 keV

Side-water cooling works at X17, but more power on NSLS-II damping wiggler - needs R&D.

Fixed Exit - modified boomerang style design

2:1 Focusing in this design. 1:1 Focusing previously at X17/X7B







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Double-Crystal Laue Monochromator



~ 150 W absorbed by first crystal. Still significant. R&D needed on cooling schemes. Maybe thinner crystals may help, but more difficult to control bending.



Horizontally Focusing Bent Graded-Multilayer

Current technology : 0.5 m. Possibly 1 m in the future.

Place as close to sample as possible for maximum focusing effect (applicable for Diamond Anvil Cell Work). 50:1 demag - 5 μ m fwhm horizontal focus.

Example Layers: Ir $(20\text{\AA})/B_4C(20\text{\AA})$ - 70 periods.







Hignette(ESRF), Rev. Sci. Instrum, 76(6), 063709, 2005 =6%). The multilayer consists of 30 W/B₄C layers with a period of 4.7 nm at the center. It has a 33% nonlinear gradient in period along the length of the mirror, designed so that the Bragg angle condition is kept despite the variation in the angle of incidence. This design is also necessary to achieve a



Flux and Beam Size at Sample Position (57.7 m)

Enegy [keV]	Flux at mirror wih 5mm Carbon [ph/sec/0.1%BW)	Flux after mirror (withdrawn above 40 kev) (ph/sec/0.1%BW)
20 40 60 80 100	4.6x10 ¹⁴ 1.7x10 ¹⁴ 3.7x10 ¹³ 7.2x10 ¹² 1.3x10 ¹²	3.7x10 ¹⁴ 1.2x10 ¹⁴

Bent Laue dE/E~1x10⁻³ Si(111). 0.5mm thick crystals + 2mm Si pre-filter. ~ 2:1 focusing

Enegy [keV]	Flux at Sample (ph/sec)	Beam Size
20	1.8x10 ¹³	300 μm[h] x 400 μm [v] / 3mm - mirror in
40	1.1x10 ¹⁴	300 μm[h] x 400 μm [v] / 3mm - mirror in
60	3.0x10 ¹³	300 μm[h] x 5mm [v]
80	6.2x10 ¹²	300 µm[h] x 5mm [v]
100	1.1x10 ¹²	300 µm[h] x 5mm [v]

Bent Laue dE/E~4x10⁻⁴ Si(311). 0.5mm thick crystals + 2mm Si pre-filter. ~ 2:1 focusing

Enegy [keV]	Flux at Sample (ph/sec)	Beam Size
20	7.2x10 ¹²	300 μm[h] x 400 μm [v] / 3mm - mirror in
40	4.4x10 ¹³	300 μm[h] x 400 μm [v] / 3mm - mirror in
60	1.2x10 ¹³	300 μm[h] x 5mm [v]
80	2.5x10 ¹²	300 μm[h] x 5mm [v]
100	4.4x10 ¹¹	300 μm[h] x 5mm [v]



Flux and Beam Size at Sample Position (57.7 m)

Unbent Laue - for hig resolution work. Si(111) dE/E ~ 1x10 ⁻⁴									
Enegy [keV]	Flux at Sample (ph/sec)	Beam Size							
20 40 60 80 100	$\begin{array}{c} 1.8 \times 10^{12} \\ 1.1 \times 10^{13} \\ 3.0 \times 10^{12} \\ 6.2 \times 10^{11} \\ 1.1 \times 10^{11} \end{array}$	5.8 cm[h] x 400 μm [v] / 3mm [v] - mirror in 5.8 cm[h] x 400 μm [v] / 3mm [v] - mirror in 5.8 cm[h] x 5mm [v] 5.8 cm[h] x 5mm [v] 5.8 cm[h] x 5mm [v]							

Now add the horizontally-focusing graded multilayer, 0.5 m long optic Ir (20Å)/ $B_4C(20Å)$ - 70 periods.

_Unbent Laue - for hig resol	ution work. Si(111) dE/E ~ 1x10	-4		
Enegy [keV]	Inc. Ang. (mrad)	Hor. Accep (mm)	Flux (ph/sec)	Beam Size
20 40 60 80	7.7 3.9 2.6 1.9	3.15 1.95 1.3 0.95	9.8x10 ¹⁰ 3.7x10 ¹¹ 6.7x10 ¹⁰ 1.0x10 ¹⁰	14 μm [h] x 400 μm [v] / 3mm [v] - mirror in 14 μm [h] x 400 μm [v] / 3mm [v] - mirror in 14 μm [h] x 5mm [v] 14 μm [h] x 5mm [v]
100	1.5	0.75	1.3x10 ⁹	14 µm [h] x 5mm [v]



Beamline Layout

<u>Key Points:</u> Power loads are critical!!! Attenutor assembly: absorb as much power as reasonable possible to guarantee a high performance stable beamline.





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Experimental Endstation 1 - Back Hutch







Key Features

High resolution diffractometer (in use in Swiss LS and Australian Light Source)

Graded Multilayer Focusing

Robot Sample Changer * not shown

Laue Analyszer Crystals

7000 element Silicon Strip Detector, fast read out (msec)



Experimental Endstation 2 - Front Hutch







Enclosure costed, equipment to be used from NSLS-I

Key Features

CCD area detector

Graded Multilayer Focusing * - not shown

Robot Sample Changer * not shown



Outstanding Issues

- Canting will open up more endstations from 2 Damping Wigglers in the high-ß straight section. Would be advantageous to increasing number of users. Also, power load issues would reduce by a factor of ~ 2.
- Thermal heat loads seem tollerable but R&D effort needed -Filters, Mirrors and Laue Mono.
- R&D required on long graded bent multilayers.





Cost Estimate

	1		_						_				
Component		1.04.05.01 Undulator Beamline 1 Inelastic X-ray Scattering		1.04.05.02 Undulator Beamline 2 Hard X-ray Nanoprobe		1.04.05.03 Undulator Beamline 3 - Hard X-ray Coherent Scattering		1.04.05.04 Undulator Beamline 4 - Soft X-ray Coherent Scattering		1.04.05.05 Damping Wiggler Beamline 1 - XAS	1.04.05.06 Damping Wiggler Beamline 2 - Powder Diffraction	Bur	dened Grand Total
Enclosures	\$	1 150 960 00	\$	1 489 445 00	\$	1 583 317 00	\$	174 598 00	\$	1 212 499 00	\$ 1 472 787 00	\$	7.083.606.00
Beam Transport	\$	685,166,00	\$	153.670.00	\$	1,565,088,00	\$	206.807.00	\$	409.495.00	\$ 375.756.00	\$	3.395.982.00
Utilities	\$	335.616.00	\$	505.074.00	\$	316.364.00	\$	227.774.00	\$	227.668.00	\$ 227.668.00	\$	1.840.164.00
High Heatload Optics	\$	976.463.00	\$	1.536.974.00	-		Ť	,	\$	2.127.744.00	\$ 1.188.811.00	\$	5.829.992.00
Beam Conditioning Optics	\$	1,921,140.00	\$	2,290,227.00	\$	1,989,884.00			\$	1,583,678.00	\$ 871,612.00	\$	8,656,541.00
Personnel Safety System	\$	183,352.00	\$	187,537.00	\$	278,181.00	\$	96,894.00	\$	183,352.00	\$ 183,352.00	\$	1,112,668.00
Equipment Protection System	\$	86,262.00	\$	86,262.00	\$	86,038.00	\$	140,144.00	\$	86,038.00	\$ 86,545.00	\$	571,289.00
White Beam Apertures							\$	262,817.00				\$	262,817.00
White Beam Components			\$	302,131.00	\$	1,278,815.00						\$	1,580,946.00
End Station 1	\$	2,522,167.00	\$	4,241,913.00	\$	3,509,501.00	\$	1,869,898.00	\$	752,988.00	\$ 3,018,162.00	\$	15,914,629.00
End Station 2					\$	3,328,590.00			\$	1,967,186.00		\$	5,295,776.00
Beamline Controls	\$	674,461.00	\$	504,235.00	\$	386,610.00	\$	120,756.00	\$	147,727.00	\$ 100,351.00	\$	1,934,140.00
Beamline Control Station	\$	35,686.00	\$	35,686.00	\$	35,686.00	\$	35,686.00	\$	38,902.00	\$ 35,686.00	\$	217,332.00
Satellite Building			\$	1,025,465.00	\$	1,392,908.00						\$	2,418,373.00
Beamline Management	\$	1,368,930.00	\$	1,574,258.00	\$	1,529,692.00	\$	1,261,295.00	\$	1,462,293.00	\$ 1,624,346.00	\$	8,820,814.00
Branching Mirror							\$	598,408.00				\$	598,408.00
Exit Slits							\$	1,102,562.00				\$	1,102,562.00
First Mirrors (m0 and M1)							\$	1,111,344.00				\$	1,111,344.00
Monochromator (m2 + gratings)							\$	1,565,745.00				\$	1,565,745.00
Polarization Selection Components							\$	243,890.00				\$	243,890.00
Retocusing Mirror							\$	2,730,113.00	-			\$	2,730,113.00
Specialized White Beam Comp							-		\$	472,353.00	\$ 351,800.00	\$	824,153.00
Grand Total	\$	9,940,203.00	\$	13,932,877.00	\$	17,280,674.00	\$	11,748,731.00	\$	10,671,923.00	\$ 9,536,876.00	\$	73,111,284.00





Summary



The proposed powder diffractometer at NSLS-II will be the US' only high-resolution instrument capable of collecting data at high energies (20 keV to 100 keV). This will make it ideal for *in situ* and time resolved studies of samples held in environmental cells.





